

INFORMATION DISCLOSURE CITATION IN AN APPLICATION		ATTY. DOCKET NO. 60188-707		SERIAL NO. 10/715433	
(PTO-1449)		APPLICANT Masayuki ENDO, et al.			
		FILING DATE November 19, 2003		GROUP 2813	
U.S. PATENT DOCUMENTS					
EXAMINER'S INITIALS	CITE NO.	Document Number Number-Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
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<i>SM</i>		Switkes, M, et al. "Immersion Lithography at 157 nm.", J. Vac. Sci. Technol., B19(6), Nov/Dec 2001, pp. 2353-2356			
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